



Mirror Issues for FELs

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Needs for a Laser source?

Coherence
Tunability
High Power
Stability





Outline

☞ Optical Resonators

- Geometry
- Mirrors
- Gain vs. Losses

☞ Wavelength Range and Tunability

- Near-Mid IR
- UV-VUV

☞ Thermal Load and Stability

- Synchrotron Radiation
- High Power FELs

☞ X-Ray Optics for Resonator-Free Devices

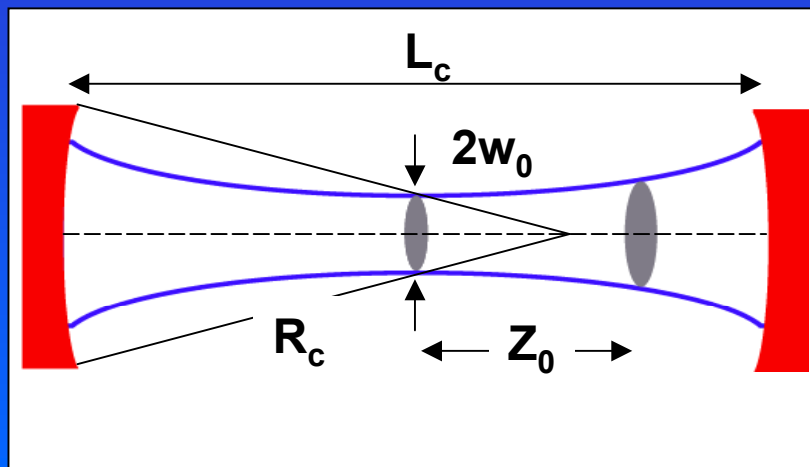
☞ Conclusions

Optical Resonators : Geometry

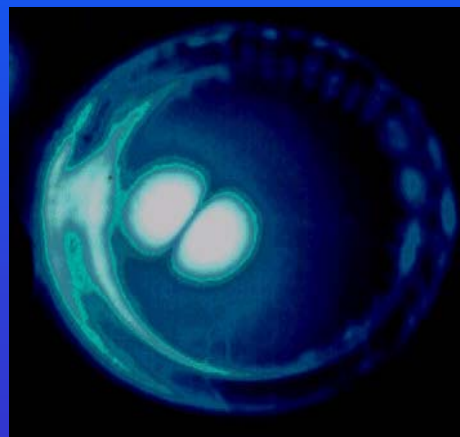
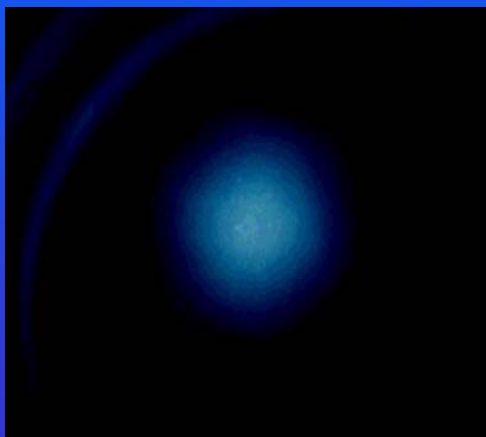


$$w_0 = \frac{\lambda}{2\pi} \sqrt{L_c (2R_c - L_c)}$$

$$Z = \frac{\pi w_0^2}{\lambda}$$



- Gauss-Hermite Modes TEM_{mn}
- Higher order modes are larger



Optical Resonators: Mirrors

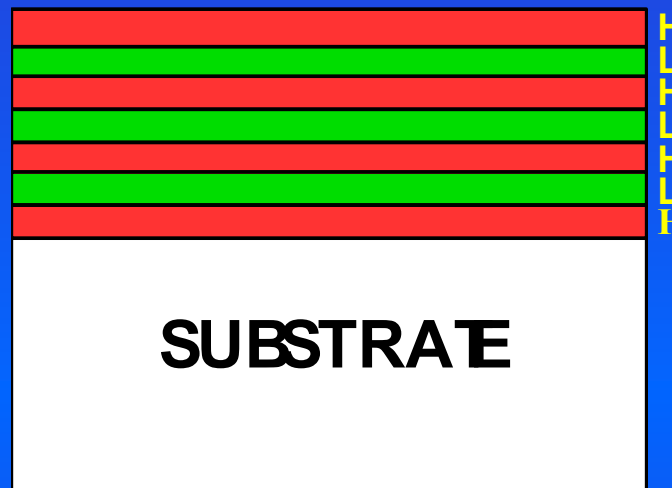


IR -> VUV

$$\tilde{n} = n + ik = 1.3 \dots 2.0$$

- *Substrate + Coated Layers*
- *optical materials:*
 - oxides, fluorides, metals
- *optical losses:*
 - absorption, scattering

transmission, reflection optics



Gain, Mirror Losses and Laser power



$$G_0 \propto N^3 \cdot \kappa^2 \cdot \gamma^{-3} \cdot \rho_e$$



$$G_0 > L$$



$$L = T + A + D$$



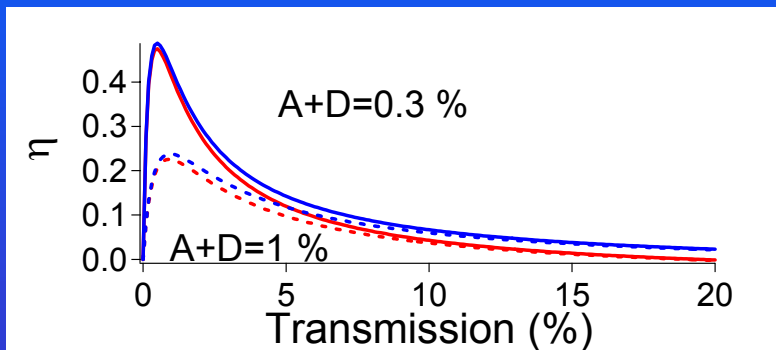
$$P_{laser} = \eta_{opt} P_{beam}$$

$$\eta_{opt} = \frac{T}{L} \cdot \left(\frac{1}{L} - \frac{1}{G_0} \right) \quad \text{for a SRFEL}$$

$$\eta_{opt} = \frac{T}{L^{3/2}} \quad \text{for non recirculating FEL}$$



- Too large transmission reduces intracavity power, thus killing the amplification process
- The amplification and the losses determine the optimal value for the transmission.





Wavelength Range and tunability



The IR range

-In the near IR range, gain values overpass the 50-100 %

-Metal Coated Mirrors (Au) or oxyde multilayers guarantee very high reflectivities

☞ How the IR FELs extended their capabilities towards the long wavelength range?

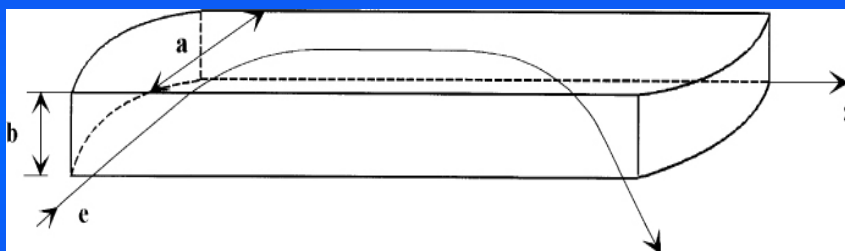
☞ Is Output Coupling a crucial factor for increase the extracted Power ?



Free Space-Waveguide Coupling

Optical Range : Free Space modes small compared to the Finite Aperture

Long Wavelengths Range : Diffraction Losses increase



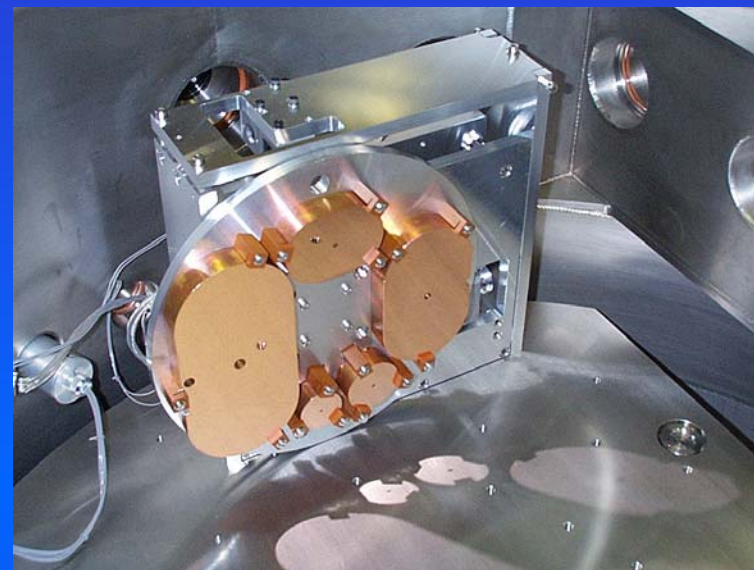
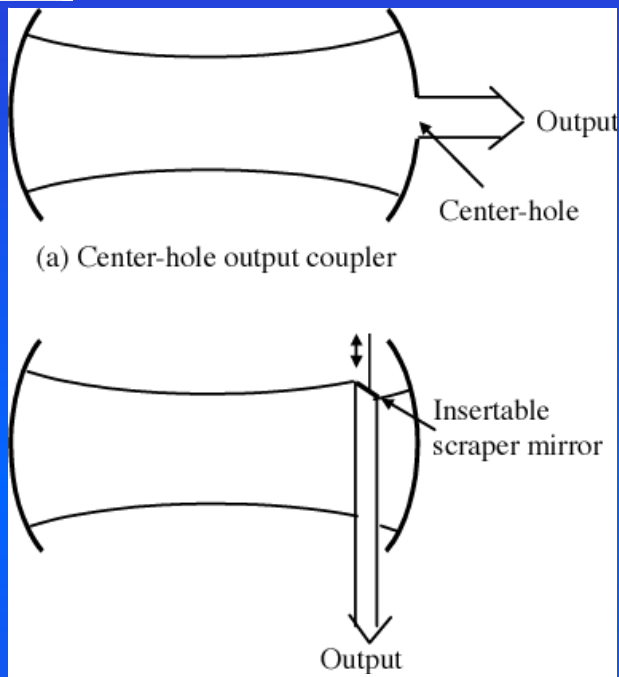
$$w_0/a = 0.352$$

- Hybrid waveguides resonators : partial waveguiding of the optical mode
high efficient TEM_{00} - TE_{10} coupling
- Toroidal Mirror are used
- High order modes are almost suppressed

A. Doria, G. Gallerano, Opt. Com 85 (1991) 500-507

K. Berryman, T. Smith, NIM A 318 (1992) 147-151

Output Coupling and Versatility



Mirrors Carrousel on the FELIX facility
 Wavelength Range : 25-300 μm

Output coupling system in JAERI FEL
 For the mid-IR range.

Optical extraction efficiency doubles
 with respect to the hole coupling

R. Nagai et al., NIM A 475 (1992) 147-151



UV-VUV Optics I

- 1983 : ACO oscillates @ 635 nm with $G < 0.5$ %
- 1987 : ACO @ 463 nm with $G \sim 0.2$ %
- 1988 : VEPP3 OK-4 @ 240-690 nm with $G = 4-10$ %

- 1992: Super ACO at high $E = 800$ MeV @ 350 nm $G \sim 2$ % $P \sim 100$'s of mW
- 1997: UVSOR Helical OK @ < 239 nm
- 1998: Duke OK-4 and NIJI-IV @ 212-226 nm 2 % $< G < 13$ %
- 1999: Duke OK-4 @ 193.7-209
- 2001: ELETTRA @ 190 nm $G \sim 20$ %

- 2001: UVSOR user experiment @ 570nm but $P \sim 1.2$ W!
- 2002: ELETTRA $E = 1.5$ GeV @ 207 nm $P \sim 0.2$ W.



UV-VUV Optics II

✓ Coatings

- Reduced number of transparent materials
- Scattering and absorption losses increased
- Contamination, environment and lifetime problems

✓ Components

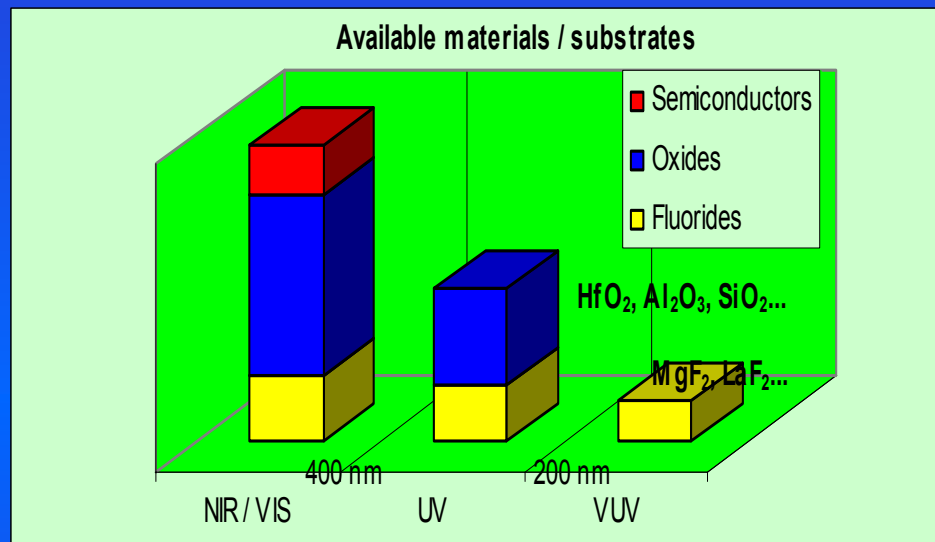
- Coating substrates with strong different thermal expansion coefficients
- Transparency (Output Coupling)

✓ General

- No commercial metrology tools available, must be developed too.



- Available technologies :
- - Ultra low loss PVD
- - Advanced Plasma Source (PIAD)
- - Ion Assisted Deposition (IAD)
- - Ion Beam Sputtering (IBS)



	248 nm	193 nm	157 nm
Fused silica	+	+	
Sapphire	+	--	--
CaF ₂	+	+	+
MgF ₂	+	+	+

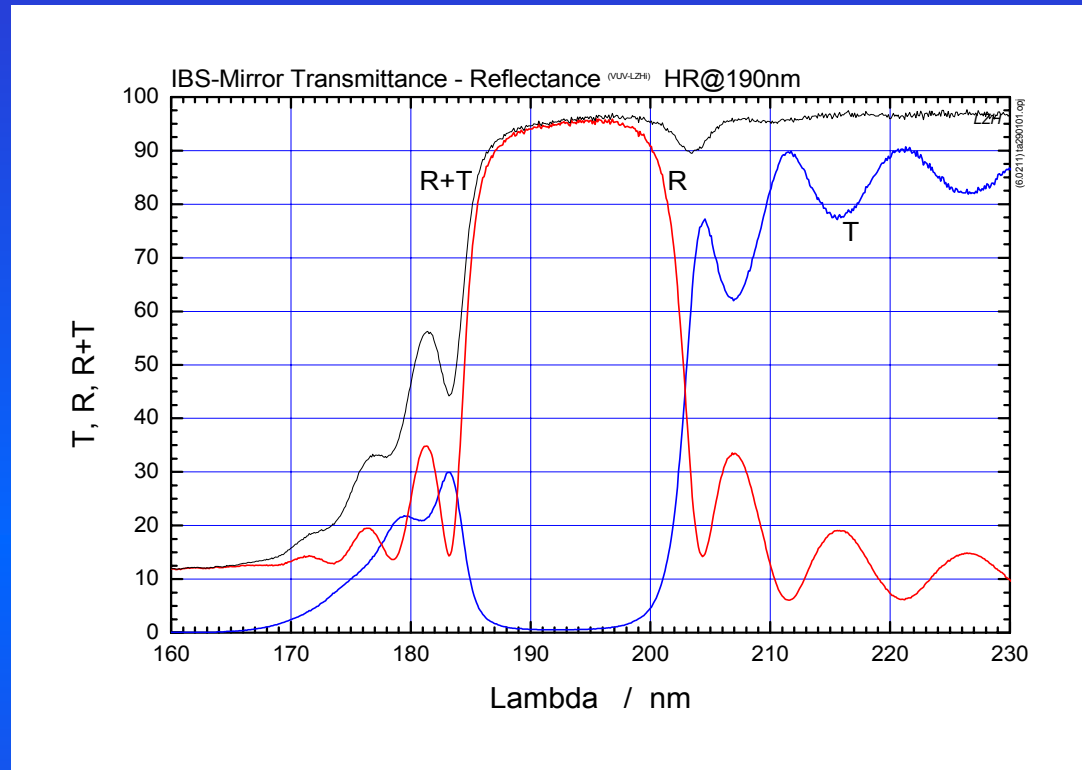
UV-VUV Optics II: State of the Art



HR @ 193 nm
 $\text{Al}_2\text{O}_3/\text{SiO}_2$ deposited by IBS

lasing at
 189.95 nm – 200.3 nm

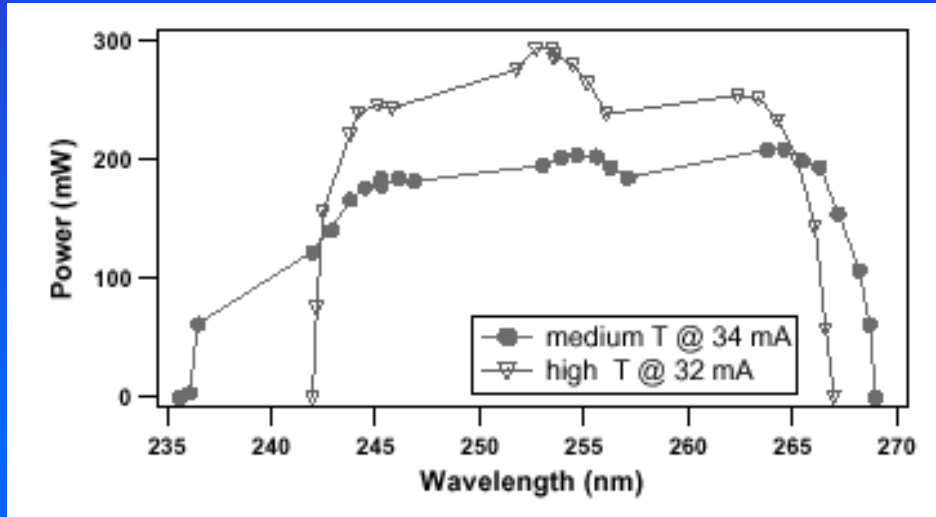
10 mW @ 26 mA



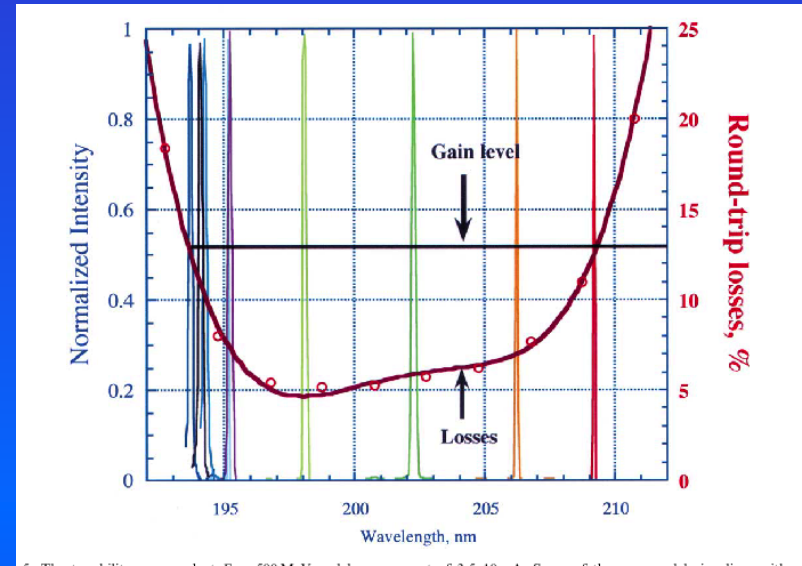
By courtesy of A. Gatto and S. Gunster



UV Tunability



ELETTRA



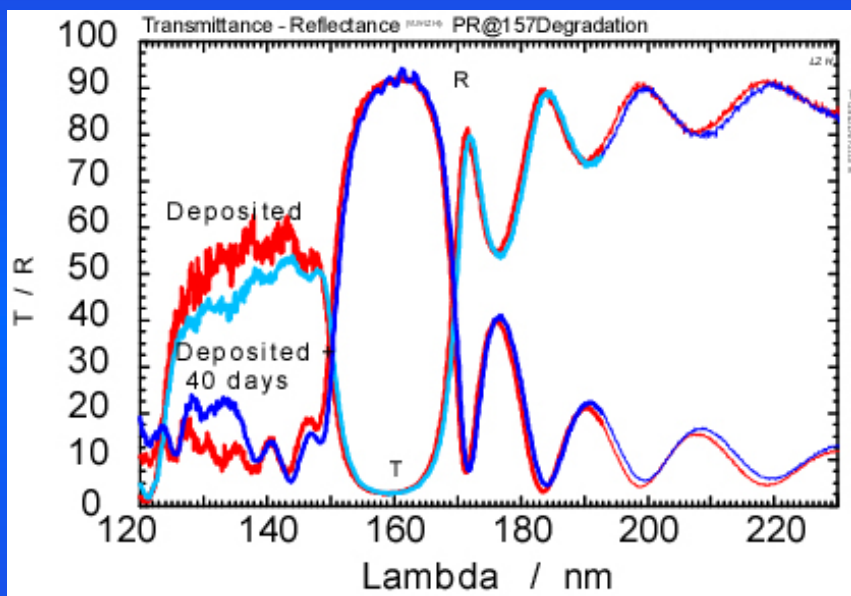
DUKE

☞ G.Swift, V. Litvinenko, Tu-P-18

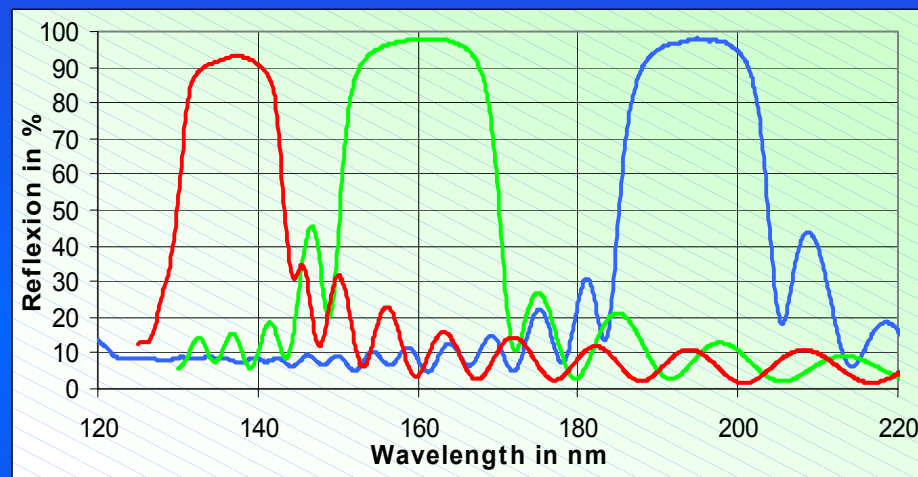
Towards shorter Wavelengths I



IBS Al₂O₃/SiO₂ multilayer



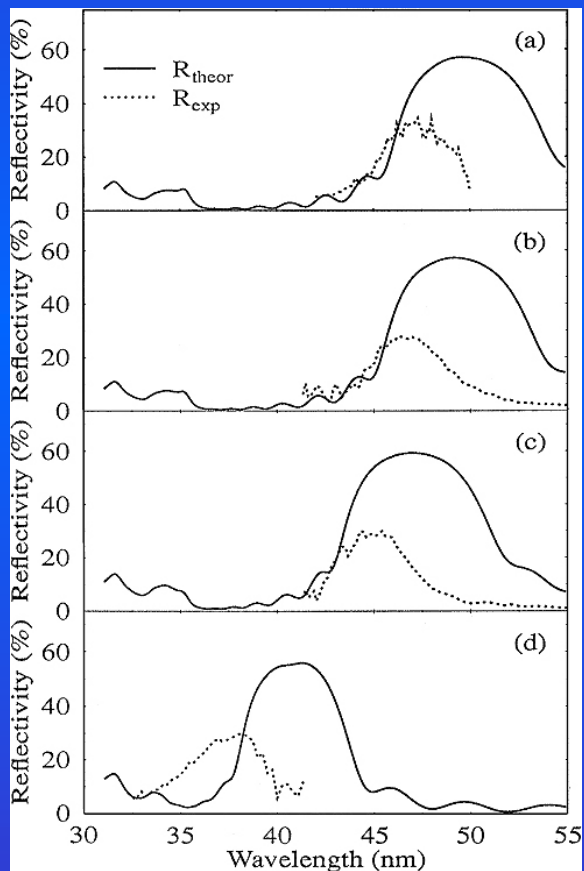
Optical indices based Calculations



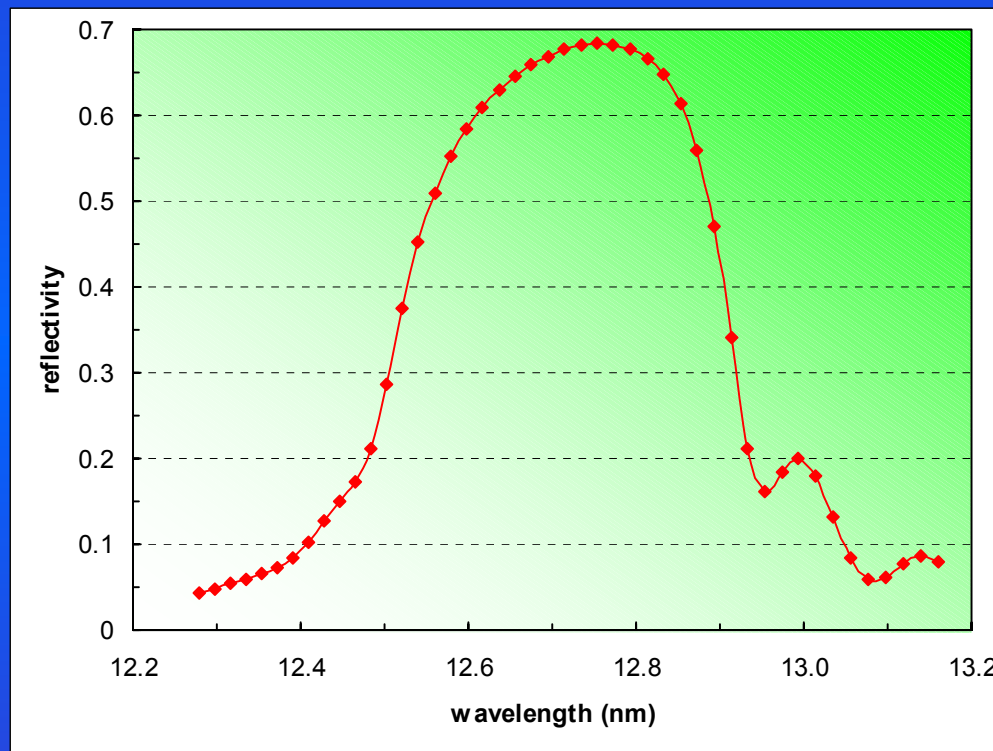
Towards shorter Wavelengths II



Sc-Si multilayer



Mo-Si multilayer



By courtesy of A. Gatto

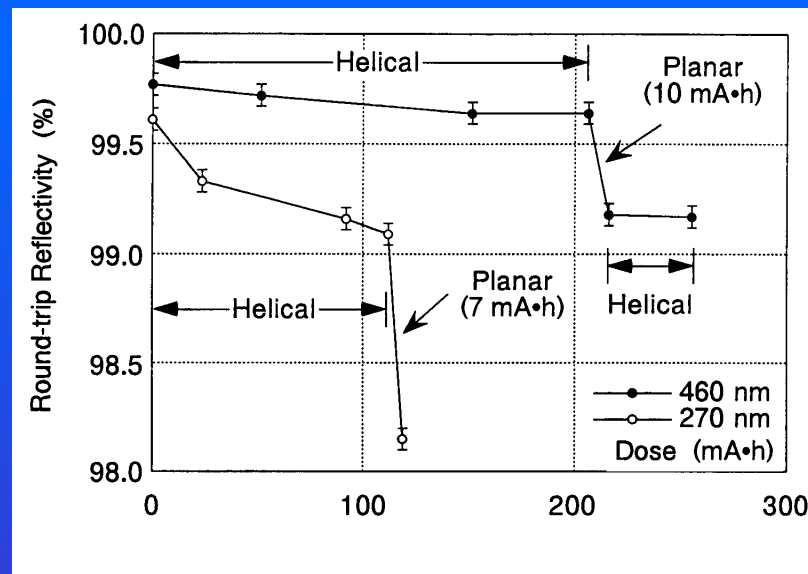


Uspenkij et al. NIM A 448 (2000) 147-151

Mirrors Degradation



- Surface Degradation
 - Residual Hydrocarbon Gases
 - VUV Harmonics from the undulator
- Volume degradation
 - Non stoichiometry
 - X-rays activation



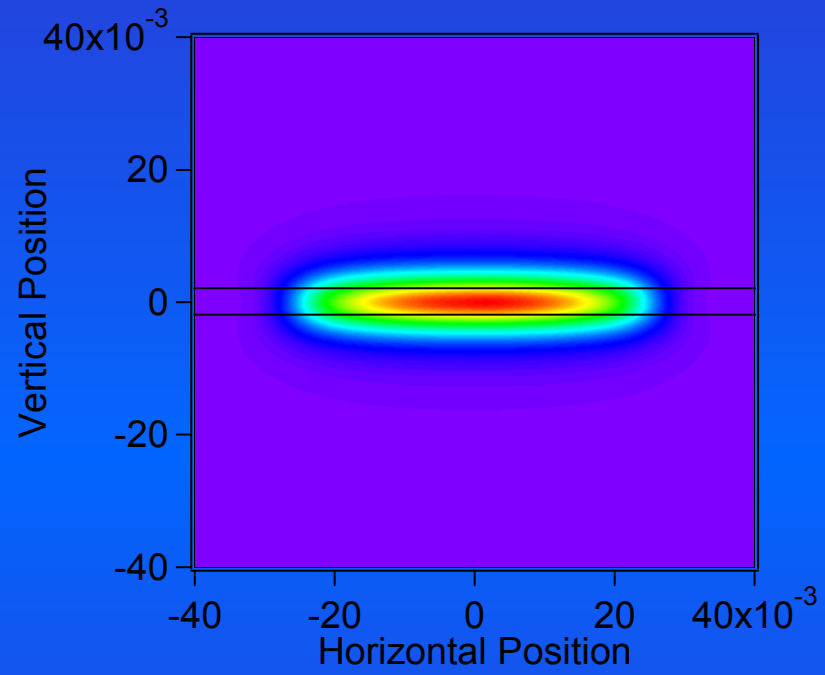
K. Yamada et al, NIM A (1995)

H. Hama et al, NIM A (1997)

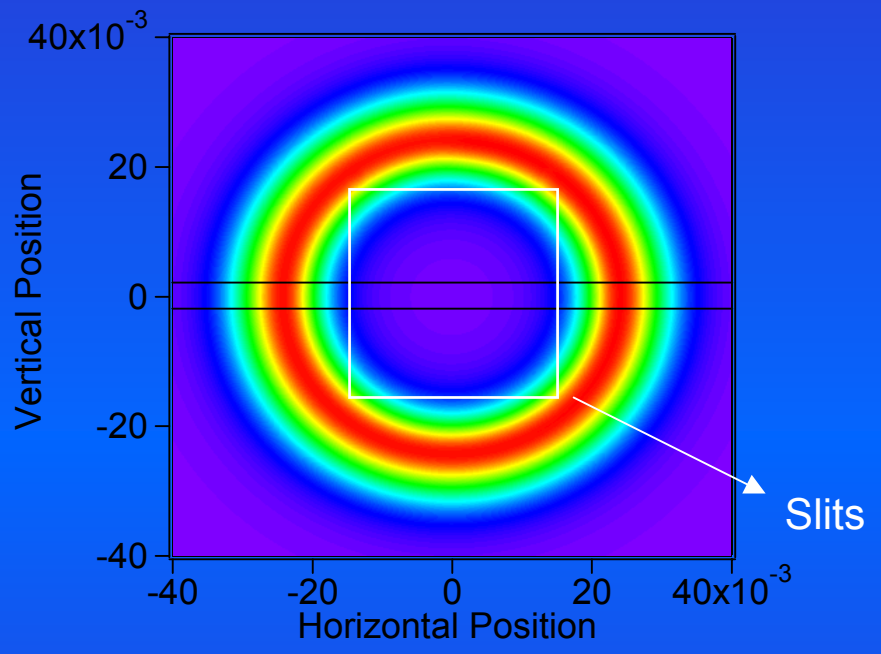
D. Garzella et al, NIM A (1996)

A. Gatto et al, NIM A 484 (2002)

Synchrotron Radiation



Planar Optical Klystron



Variable Polarization Optical Klystron

Calculations performed with the SRW code (by P. Elleaume and O. Chobar)

Mirrors Degradation

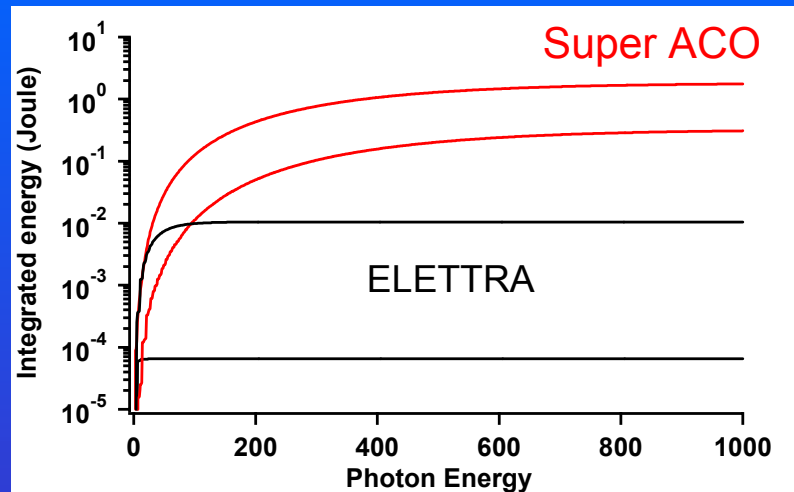
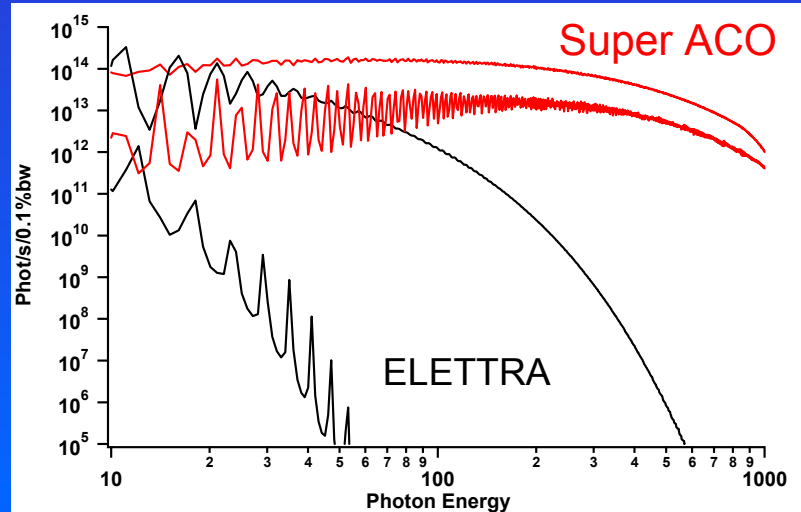


Synchrotron Radiation
 spectral content

Investigated Areas : 5 x 5 mm
 20 x 20 mm

Total energy deposited
 on the Surface

Has Irradiated Dose (mAh)
 a meaning anymore?



High damage Threshold



LIDT scales as $1/\lambda$ and decrease with pulse length

Wavelength (nm)	Coating	Pulse width	LIDT (J/cm ²)	Scaled 248 nm LIDT (J/cm ²)
355	Fluoride	3 ns	12	0.2
355	Oxide	3 ns	12	0.2
248	Oxide	30 ns	16	0.1
248	Oxide	20 ns	2.5	0.02
193	Oxide	30 ns	0.5	0.003
193	Fluoride	30 ns	6.7	0.04
800	Oxide	100 fs	0.4	0.1

By courtesy of M. Shinn

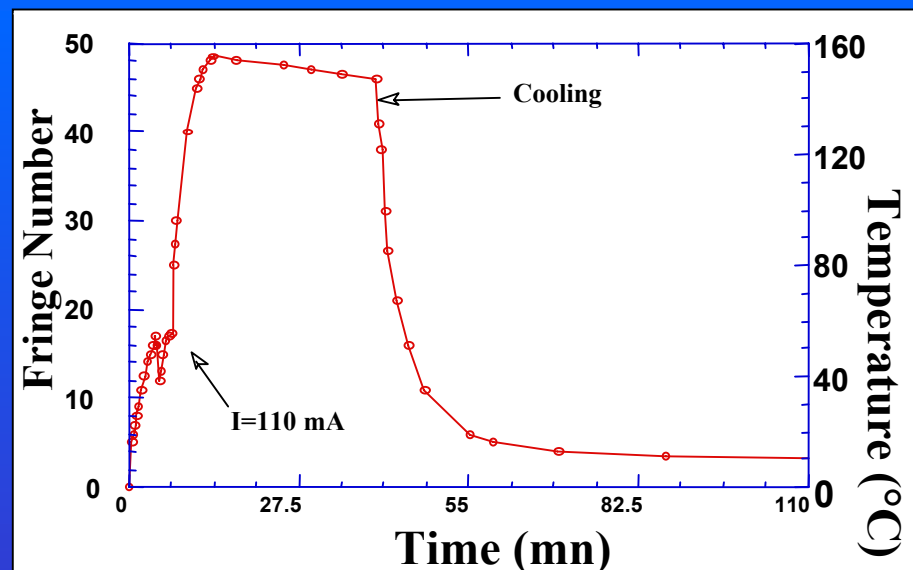
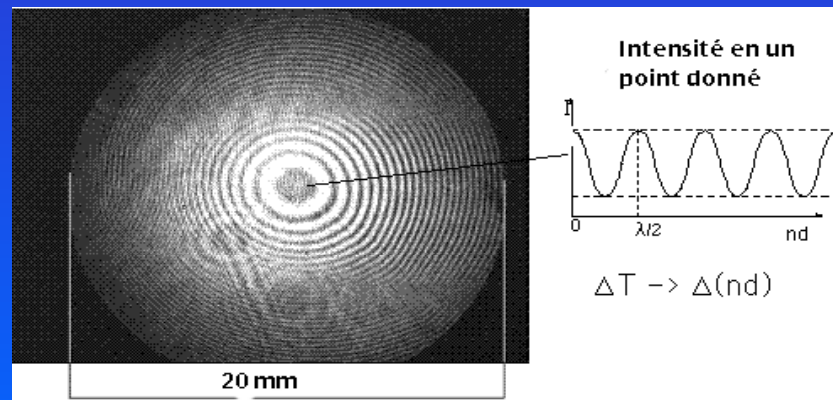


Thermal Load and Stability

Synchrotron Power



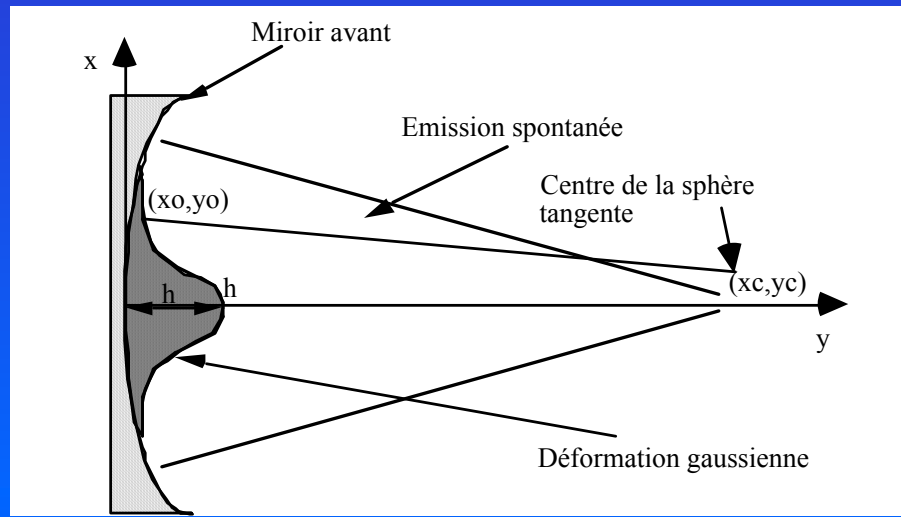
$$P(W) = 7.28 E^2 (\text{GeV}) N I (A) \frac{K^2}{\lambda_0 (\text{cm})}$$



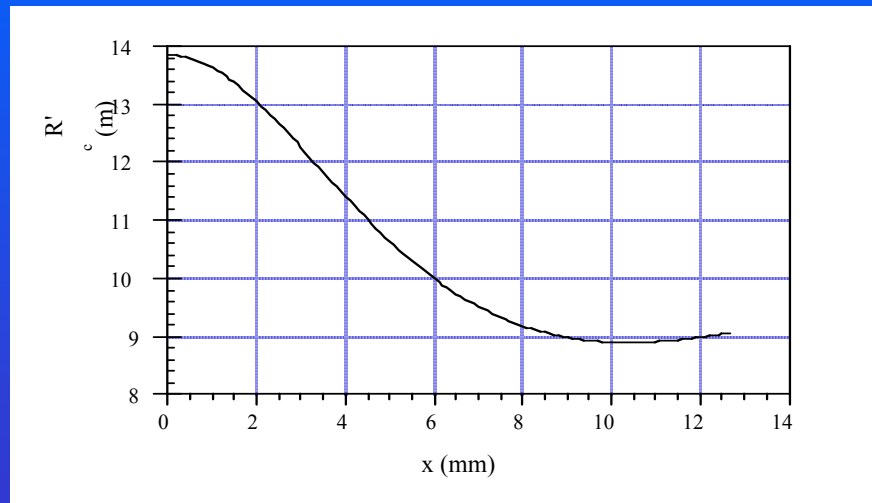
Synchrotron Power



$$y(x) = \frac{x^2}{2R_c} + h_{Th} e^{-\frac{x^2}{2\sigma_{Th}^2}}$$



$$\frac{1}{R_c} - \frac{h_{Th}}{\sigma_{Th}^2} e^{-\frac{x_0^2}{2\sigma_{Th}^2}} \left(1 - \frac{x_0^2}{\sigma_{Th}^2} \right) = \frac{1}{R'_c}$$

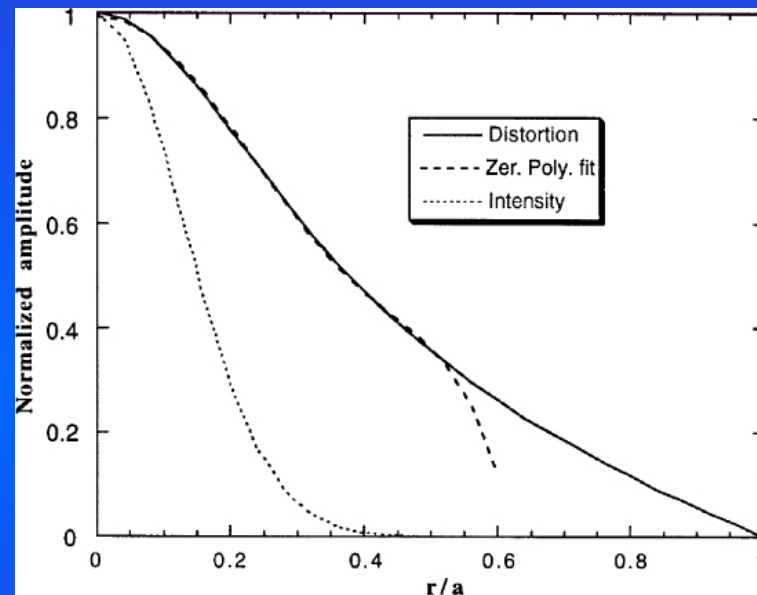




High Power FEL Operation

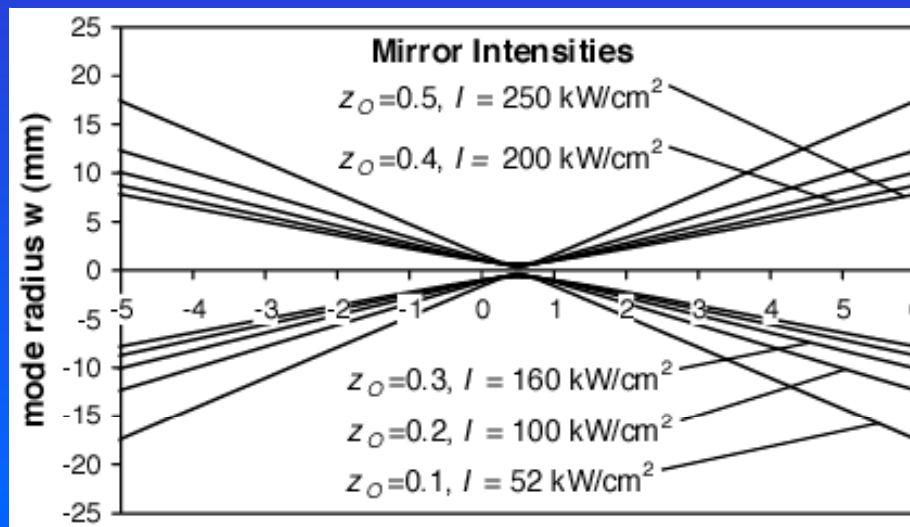
Non negligible amount of FEL power is absorbed (10's of W)

Transient and steady-state mode distortion has been observed





High Power FEL Operation



-Thermal Load is reduced by shortening the Rayleigh Length

-Concentric Resonator configuration (more unstable)?

👉 M. D. Shinn Tu-O-06



X-Ray Optics I : Reflective Optics

Spatial Coherence, High Brilliance



Imaging
Interferometry
Non linear Optics

➤ Surface State

Roughness $\ll 1\text{nm}$

Figure Errors $< \lambda$

➤ Thermal constraints

➤ Damage Thresholds

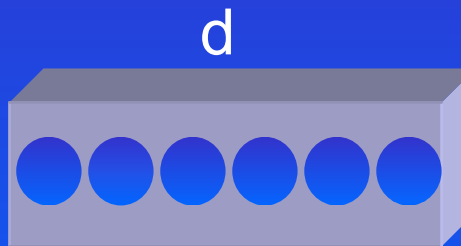
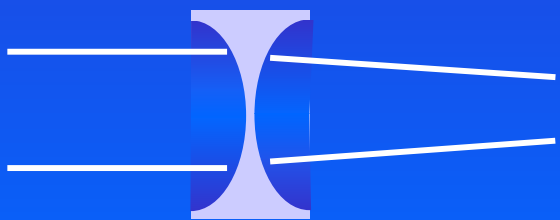
☞ J. Kuba Th-O-04

☞ B. Steeg Tu-P-30

X-Ray optics II : Refractive Optics



$$\text{Re}(n) = 1 - \delta \quad \delta \approx 10^{-4} - 10^{-6}$$



$$f \cong \frac{r}{2N\delta} \quad N \approx 50 - 100$$

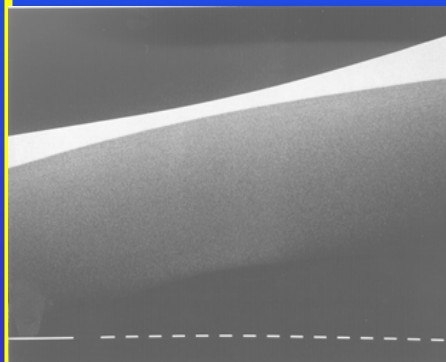
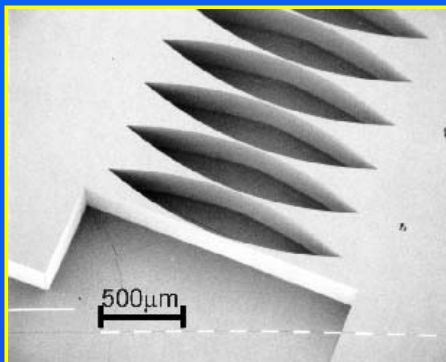
$$f \cong \frac{r}{2\delta} \quad r \approx 100 \mu\text{m} - \text{few mm}$$



δ (Al) $2.8 \cdot 10^{-6}$ $\lambda = 0.9 \text{ \AA}$

$$f \cong 200 \text{ m} !!$$

By courtesy of R. Kupka



**LIGA process
 on PMMA**

$r = 1 - 2 \text{ mm}$

$d = 10 \text{ mm}$

$\delta = 1.6 \cdot 10^{-6} \lambda^2$

$N = 100$

$f \approx \text{few mm}$



Conclusions

- Optical Resonator development is linked to the extension of user applications domain.
- High Damage threshold studies in the UV and mirror degradation by Synchrotron Radiation (cf. Fluorides) are still major issues.
- Research & Development in UV-VUV Optics for FEL still has a large interest, provided that improvement of the gain progresses as well.

Acknowledgments

M.E. Couprie and the Super ACO FEL team

The ELETTRA FEL Team

M. Shinn and S. Benson

A.Gatto, T. Feigl and S. Gunster